



AMENDMENT UNDER 37 C.F.R. § 1.116 EXPEDITED PROCEDURE GROUP 2826 PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q77191

Koichi OHTO, et al.

Appln. No.: 10/650,193

Group Art Unit: 2826

Confirmation No.: 6245

Examiner: Alexander O. WILLIAMS

Filed: August 28, 2003

For:

SEMICONDUCTOR DEVICE HAVING SILICON-DIFFUSED METAL WIRING

LAYER AND ITS MANUFACTURING METHOD

AMENDMENT UNDER 37 C.F.R. § 1.116

MAIL STOP AF

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated August 1, 2006, please amend the above-identified application as follows on the accompanying pages.

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